

Notice of References CitedApplication/Control No.
10/805,871Applicant(s)/Patent Under
Reexamination
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Natasha YoungArt Unit
1797

Page 1 of 1

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*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)
Dates in MM-YYYY format are publication dates. Classifications may be US or foreign.